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PASSWORD:

TERMINAL (ENTER 1, 2, 3, OR ?):2

\* \* \* \* \* Welcome to STN International \* \* \* \* \*

NEWS	1		Web Page for STN Seminar Schedule - N. America
NEWS	2	JAN 02	STN pricing information for 2008 now available
NEWS	3	JAN 16	CAS patent coverage enhanced to include exemplified prophetic substances
NEWS	4	JAN 28	USPATFULL, USPAT2, and USPATOLD enhanced with new custom IPC display formats
NEWS	5	JAN 28	MARPAT searching enhanced
NEWS	6	JAN 28	USGENE now provides USPTO sequence data within 3 days of publication
NEWS	7	JAN 28	TOXCENTER enhanced with reloaded MEDLINE segment
NEWS	8	JAN 28	MEDLINE and LMEDLINE reloaded with enhancements
NEWS	9	FEB 08	STN Express, Version 8.3, now available
NEWS	10	FEB 20	PCI now available as a replacement to DPCI
NEWS	11	FEB 25	IFIREF reloaded with enhancements
NEWS	12	FEB 25	IMSPRODUCT reloaded with enhancements
NEWS	13	FEB 29	WPINDEX/WPIDS/WPIX enhanced with ECLA and current U.S. National Patent Classification
NEWS	14	MAR 31	IFICDB, IFIPAT, and IFIUDB enhanced with new custom IPC display formats
NEWS	15	MAR 31	CAS REGISTRY enhanced with additional experimental spectra
NEWS	16	MAR 31	CA/CAPplus and CASREACT patent number format for U.S. applications updated
NEWS	17	MAR 31	LPCI now available as a replacement to LDPCI
NEWS	18	MAR 31	EMBASE, EMBAL, and LEMBASE reloaded with enhancements
NEWS	19	APR 04	STN AnaVist, Version 1, to be discontinued
NEWS	20	APR 15	WPIDS, WPINDEX, and WPIX enhanced with new predefined hit display formats
NEWS	21	APR 28	EMBASE Controlled Term thesaurus enhanced
NEWS	22	APR 28	IMSRESEARCH reloaded with enhancements
NEWS	23	MAY 30	INPAFAMDB now available on STN for patent family searching
NEWS	24	MAY 30	DGENE, PCTGEN, and USGENE enhanced with new homology sequence search option
NEWS	25	JUN 06	EPFULL enhanced with 260,000 English abstracts
NEWS	26	JUN 06	KOREAPAT updated with 41,000 documents
NEWS EXPRESS		FEBRUARY 08	CURRENT WINDOWS VERSION IS V8.3, AND CURRENT DISCOVER FILE IS DATED 20 FEBRUARY 2008
NEWS HOURS			STN Operating Hours Plus Help Desk Availability
NEWS LOGIN			Welcome Banner and News Items
NEWS IPC8			For general information regarding STN implementation of IPC 8

Enter NEWS followed by the item number or name to see news on that specific topic.

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\* \* \* \* \* STN Columbus \* \* \* \* \*

FILE 'HOME' ENTERED AT 16:04:09 ON 11 JUN 2008

=> file reg

COST IN U.S. DOLLARS

SINCE FILE

TOTAL

ENTRY

SESSION

FULL ESTIMATED COST

0.21

0.21

FILE 'REGISTRY' ENTERED AT 16:04:13 ON 11 JUN 2008

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STRUCTURE FILE UPDATES: 10 JUN 2008 HIGHEST RN 1027136-44-2

DICTIONARY FILE UPDATES: 10 JUN 2008 HIGHEST RN 1027136-44-2

New CAS Information Use Policies, enter HELP USAGETERMS for details.

TSCA INFORMATION NOW CURRENT THROUGH January 9, 2008.

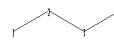
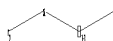
Please note that search-term pricing does apply when conducting SmartSELECT searches.

REGISTRY includes numerically searchable data for experimental and predicted properties as well as tags indicating availability of experimental property data in the original document. For information on property searching in REGISTRY, refer to:

<http://www.cas.org/support/stngen/stndoc/properties.html>

=>

Uploading C:\Program Files\Stnexp\Queries\10765366\str1.str



```
chain nodes :
1  2  3  4
chain bonds :
1-2  2-3  3-4
exact/norm bonds :
1-2
exact bonds :
2-3  3-4
```

G1:MeO,EtO

G2:MeO,EtO

```
Match level :
1:CLASS  2:CLASS  3:CLASS  4:CLASS
```

L1        STRUCTURE UPLOADED

```
=> s l1
SAMPLE SEARCH INITIATED 16:04:30 FILE 'REGISTRY'
SAMPLE SCREEN SEARCH COMPLETED -     26181 TO ITERATE
```

```
7.6% PROCESSED        2000 ITERATIONS
INCOMPLETE SEARCH (SYSTEM LIMIT EXCEEDED)
SEARCH TIME: 00.00.01
```

50 ANSWERS

```
FULL FILE PROJECTIONS:  ONLINE  **COMPLETE**
                         BATCH   **COMPLETE**
PROJECTED ITERATIONS:        513939 TO    533301
PROJECTED ANSWERS:            45230 TO    51116
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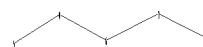
L2                    50 SEA SSS SAM L1

=> s l1 ful  
FULL SEARCH INITIATED 16:04:34 FILE 'REGISTRY'  
FULL SCREEN SEARCH COMPLETED -    522230 TO ITERATE

100.0% PROCESSED    522230 ITERATIONS                    42441 ANSWERS  
SEARCH TIME: 00.00.02

L3                    42441 SEA SSS FUL L1

=>  
Uploading C:\Program Files\Stnexp\Queries\10765366\str2.str



chain nodes :  
4 5 6 7 8  
chain bonds :  
4-5 4-6 6-7 7-8  
exact/norm bonds :  
4-5 7-8  
exact bonds :  
4-6 6-7

G1:MeO,EtO

G2:CH3,CF3

Match level :  
4:CLASS 5:CLASS 6:CLASS 7:CLASS 8:CLASS

L4                    STRUCTURE UPLOADED

=> s l4 ful

FULL SEARCH INITIATED 16:04:56 FILE 'REGISTRY'  
FULL SCREEN SEARCH COMPLETED - 23275 TO ITERATE

100.0% PROCESSED 23275 ITERATIONS 677 ANSWERS  
SEARCH TIME: 00.00.13

L5 677 SEA SSS FUL L4

=> s 13 and 15

L6 677 L3 AND L5

=> file caplus

COST IN U.S. DOLLARS	SINCE FILE ENTRY	TOTAL SESSION
FULL ESTIMATED COST	356.72	356.93

FILE 'CAPLUS' ENTERED AT 16:05:21 ON 11 JUN 2008  
USE IS SUBJECT TO THE TERMS OF YOUR STN CUSTOMER AGREEMENT.  
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FILE COVERS 1907 - 11 Jun 2008 VOL 148 ISS 24  
FILE LAST UPDATED: 10 Jun 2008 (20080610/ED)

Effective October 17, 2005, revised CAS Information Use Policies apply. They are available for your review at:

<http://www.cas.org/legal/infopolicy.html>

=> s 16

L7 1871 L6

=> s 17 and silicon

883161 SILICON

421 SILICONS

883305 SILICON

(SILICON OR SILICONS)

L8 329 L7 AND SILICON

=> s 18 and ((vapor (a) depos?) or cvd or pecvd)

564157 VAPOR

74017 VAPORS

607606 VAPOR

(VAPOR OR VAPORS)

988146 DEPOS?

193233 VAPOR (A) DEPOS?

76827 CVD

83 CVDS

76848 CVD

(CVD OR CVDS)

8624 PECVD

L9 49 L8 AND ((VAPOR (A) DEPOS?) OR CVD OR PECVD)

=> dup remove l9

PROCESSING COMPLETED FOR L9

L10 49 DUP REMOVE L9 (0 DUPLICATES REMOVED)

=> d ti 1-49

L10 ANSWER 1 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN

TI Layer-by-layer fabrication of broad-band super-hydrophobic antireflection coatings in near-infrared region

L10 ANSWER 2 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN

TI Digital magnetofluidic devices and methods

L10 ANSWER 3 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN

TI Method of processing a biological and/or chemical sample

L10 ANSWER 4 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN

TI Thin organic alignment layers with a batch process for liquid crystal displays

L10 ANSWER 5 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN

TI Atmospheric plasma deposition of hydrophobic/oil-repellent coatings with improved durability on glass/ceramic windows

L10 ANSWER 6 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN

TI Method for constructing surface enhanced substrate with metal ordered structure

L10 ANSWER 7 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN

TI Reproducible microfabrication method for a metal oxide film on a chemical template of self-assembled monolayer

L10 ANSWER 8 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN

TI Method of forming self-organizing monomolecular film and utilization of the same

L10 ANSWER 9 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN

TI Falling acceleration of droplets on the water-repellent solid surface and control methods therefor and structures having controlled water-repellent solid surfaces

L10 ANSWER 10 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN

TI Method for identical dye molecule emitting different color fluorescent light by substrate induction

L10 ANSWER 11 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN

TI Surface modification of silicon and polydimethylsiloxane surfaces with vapor-phase-deposited ultrathin fluorosilane films for biomedical nanodevices

L10 ANSWER 12 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN

TI Rain-proof glass windows with a silicon-containing hydrophobic surface of improved durability

L10 ANSWER 13 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN

TI Fabrication of Superhydrophobic Surfaces by Self-Assembly and Their Water-Adhesion Properties

L10 ANSWER 14 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN

TI Micropatterning of SrBi<sub>2</sub>Ta<sub>2</sub>O<sub>9</sub> ferroelectric thin films using a selective

deposition technique combined with patterned self-assembled monolayers and liquid-source misted chemical deposition

- L10 ANSWER 15 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
TI Nanoscale patterning of protein using electron beam lithography of organosilane self-assembled monolayers
- L10 ANSWER 16 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
TI Macro- and nanotribological properties of organosilane monolayers prepared by a chemical vapor adsorption method on silicon substrates
- L10 ANSWER 17 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
TI Thin film forming method and thin film forming substance
- L10 ANSWER 18 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
TI Method of coating microelectromechanical devices
- L10 ANSWER 19 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
TI Antisoiling optical films with good oil repellency and displays equipped therewith
- L10 ANSWER 20 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
TI Development of substrate surface modification methods for biochemical immobilization in biochips
- L10 ANSWER 21 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
TI Method and apparatus for manufacturing anti-reflective films
- L10 ANSWER 22 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
TI Formation of molecular templates for fabricating on-chip biosensing devices
- L10 ANSWER 23 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
TI Vapor pressures of precursors for the CVD of silicon-based films
- L10 ANSWER 24 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
TI Self-assembled monolayer coatings on nanostencils for the reduction of materials adhesion
- L10 ANSWER 25 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
TI Preparation of hard and ultra water-repellent silicon oxide films by microwave plasma-enhanced CVD at low substrate temperatures
- L10 ANSWER 26 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
TI Imaging micropatterned organosilane self-assembled monolayers on silicon by means of scanning electron microscopy and Kelvin probe force microscopy
- L10 ANSWER 27 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
TI Method for making thin film and electronic apparatus
- L10 ANSWER 28 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
TI Formation method of silicon thin film
- L10 ANSWER 29 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
TI Regulation of the surface potential of silicon substrates in micrometer scale with organosilane self-assembled monolayers
- L10 ANSWER 30 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
TI Surface potential images of self-assembled monolayers patterned by

organosilanes. Ab initio molecular orbital calculations

- L10 ANSWER 31 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
TI Lateral force on fluoroalkylsilane self-assembled monolayers dependent on molecular ordering
- L10 ANSWER 32 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
TI Surface potential contrasts between silicon surfaces covered and uncovered with an organosilane self-assembled monolayer
- L10 ANSWER 33 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
TI Preparation of water-repellent hard surface
- L10 ANSWER 34 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
TI Formation of surface expansion pattern and substrate having the pattern
- L10 ANSWER 35 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
TI  $\zeta$ -Potentials of planar silicon plates covered with alkyl- and fluoroalkylsilane self-assembled monolayers
- L10 ANSWER 36 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
TI Vapor deposition targets for antistaining or water-repellent coatings and antireflective materials having the coatings
- L10 ANSWER 37 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
TI Micropatterning of Alkyl- and Fluoroalkylsilane Self-Assembled Monolayers Using Vacuum Ultraviolet Light
- L10 ANSWER 38 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
TI Morphology of mesoporous silica grown on organic surfaces: effects of surface functional groups and microstructures
- L10 ANSWER 39 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
TI Method for providing water-repellent coatings on optical substrates
- L10 ANSWER 40 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
TI Water-repellent silicon oxide film, its manufacture, and hard water-repellent silicon oxide film
- L10 ANSWER 41 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
TI Preparation of functionally graded films by microwave plasma-enhanced chemical vapor deposition. Silicon oxide films having water-repellent surfaces
- L10 ANSWER 42 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
TI Preparation of silicon oxide films having a water-repellent layer by multiple-step microwave plasma-enhanced chemical vapor deposition
- L10 ANSWER 43 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
TI Effects of methyl and perfluoro-alkyl groups on water repellency of silicon oxide films prepared by microwave plasma-enhanced chemical vapor deposition
- L10 ANSWER 44 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
TI Coating of transparent water-repellent thin films by plasma-enhanced CVD
- L10 ANSWER 45 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
TI Manufacture of water-repellent coatings by high-frequency plasma chemical vapor deposition



L10 ANSWER 46 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
 TI Fluorine-contained films with high water-repellency and transparency prepared by RF plasma-enhanced CVD

L10 ANSWER 47 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
 TI Effects of substrate temperature on properties of fluorine contained silicon oxide films prepared by microwave plasma-enhanced CVD

L10 ANSWER 48 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
 TI Water-repellent fluorine-containing silicon oxide coatings

L10 ANSWER 49 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
 TI Heat- and chemical-resistant organic thin films and their manufacture

=> d bib 1-49

L10 ANSWER 1 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
 AN 2008:78111 CAPLUS  
 DN 148:333398  
 TI Layer-by-layer fabrication of broad-band super-hydrophobic antireflection coatings in near-infrared region  
 AU Zhang, Lianbin; Li, Yang; Sun, Junqi; Shen, Jiacong  
 CS State Key Lab of Supramolecular Structure and Materials, College of Chemistry, Jilin University, Changchun, 130012, Peop. Rep. China  
 SO Journal of Colloid and Interface Science (2008), 319(1), 302-308  
 CODEN: JCISA5; ISSN: 0021-9797  
 PB Elsevier  
 DT Journal  
 LA English  
 RE.CNT 49 THERE ARE 49 CITED REFERENCES AVAILABLE FOR THIS RECORD  
 ALL CITATIONS AVAILABLE IN THE RE FORMAT

L10 ANSWER 2 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
 AN 2007:1000213 CAPLUS  
 DN 147:355832  
 TI Digital magnetofluidic devices and methods  
 IN Hernandez, Sonia Melle; Gomez, Ana N.; Picraux, S. Thomas; Gust, John Devens; Hayes, Mark; Lindsay, Solitaire; Garcia, Antonio A.; Wang, Joseph; Vazquez-Alvarez, Terannie  
 PA Arizona Board of Regents for and on Behalf of Arizona State University, USA  
 SO PCT Int. Appl., 118pp.  
 CODEN: PIXXD2  
 DT Patent  
 LA English  
 FAN.CNT 1

	PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
PI	WO 2007101174	A2	20070907	WO 2007-US62842	20070227
	WO 2007101174	A3	20071221		
	W:	AE, AG, AL, AM, AT, AU, AZ, BA, BB, BG, BR, BW, BY, BZ, CA, CH, CN, CO, CR, CU, CZ, DE, DK, DM, DZ, EC, EE, EG, ES, FI, GB, GD, GE, GH, GM, GT, HN, HR, HU, ID, IL, IN, IS, JP, KE, KG, KM, KN, KP, KR, KZ, LA, LC, LK, LR, LS, LT, LU, LV, LY, MA, MD, MG, MK, MN, MW, MX, MY, MZ, NA, NG, NI, NO, NZ, OM, PG, PH, PL, PT, RO, RS, RU, SC, SD, SE, SG, SK, SL, SM, SV, SY, TJ, TM, TN, TR, TT, TZ, UA, UG, US, UZ, VC, VN, ZA, ZM, ZW			
	RW:	AT, BE, BG, CH, CY, CZ, DE, DK, EE, ES, FI, FR, GB, GR, HU, IE, IS, IT, LT, LU, LV, MC, NL, PL, PT, RO, SE, SI, SK, TR, BF, BJ, CF, CG, CI, CM, GA, GN, GQ, GW, ML, MR, NE, SN, TD, TG, BW, GH,			

GM, KE, LS, MW, MZ, NA, SD, SL, SZ, TZ, UG, ZM, ZW, AM, AZ, BY,  
 KG, KZ, MD, RU, TJ, TM, AP, EA, EP, OA  
 PRAI US 2006-777679P P 20060227

L10 ANSWER 3 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
 AN 2007:933138 CAPLUS  
 DN 147:290978  
 TI Method of processing a biological and/or chemical sample  
 IN Pipper, Juergen; Hsieh, Tseng-Ming; Neuzil, Pavel  
 PA Agency for Science, Technology and Research, Singapore  
 SO PCT Int. Appl., 67pp.  
 CODEN: PIXXD2  
 DT Patent  
 LA English  
 FAN.CNT 1

	PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
PI	WO 2007094739	A1	20070823	WO 2006-SG29	20060213
	W: AE, AG, AL, AM, AT, AU, AZ, BA, BB, BG, BR, BW, BY, BZ, CA, CH, CN, CO, CR, CU, CZ, DE, DK, DM, DZ, EC, EE, EG, ES, FI, GB, GD, GE, GH, GM, HR, HU, ID, IL, IN, IS, JP, KE, KG, KM, KN, KP, KR, KZ, LC, LK, LR, LS, LT, LU, LV, LY, MA, MD, MG, MK, MN, MW, MX, MZ, NA, NG, NI, NO, NZ, OM, PG, PH, PL, PT, RO, RU, SC, SD, SE, SG, SK, SL, SM, SY, TJ, TM, TN, TR, TT, TZ, UA, UG, US, UZ, VC, VN, YU, ZA, ZM, ZW				
	RW: AT, BE, BG, CH, CY, CZ, DE, DK, EE, ES, FI, FR, GB, GR, HU, IE, IS, IT, LT, LU, LV, MC, NL, PL, PT, RO, SE, SI, SK, TR, BF, BJ, CF, CG, CI, CM, GA, GN, GQ, GW, ML, MR, NE, SN, TD, TG, BW, GH, GM, KE, LS, MW, MZ, NA, SD, SL, SZ, TZ, UG, ZM, ZW, AM, AZ, BY, KG, KZ, MD, RU, TJ, TM				

PRAI WO 2006-SG29 20060213  
 RE.CNT 5 THERE ARE 5 CITED REFERENCES AVAILABLE FOR THIS RECORD  
 ALL CITATIONS AVAILABLE IN THE RE FORMAT

L10 ANSWER 4 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
 AN 2007:970042 CAPLUS  
 DN 147:288568  
 TI Thin organic alignment layers with a batch process for liquid crystal displays  
 IN Ong, Hiap L.  
 PA Kyoritsu Optronics Co., Ltd., Taiwan  
 SO U.S. Pat. Appl. Publ., 16pp., Cont.-in-part of U.S. Ser. No. 227,570.  
 CODEN: USXXCO

DT Patent  
 LA English  
 FAN.CNT 2

	PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
PI	US 20070202253	A1	20070830	US 2006-607246	20061201
	US 20070059438	A1	20070315	US 2005-227570	20050915
	CN 101191198	A	20080604	CN 2007-10165733	20071106
PRAI	US 2005-227570	A2	20050915		
	US 2006-607246	A	20061201		

L10 ANSWER 5 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
 AN 2007:1449167 CAPLUS  
 DN 148:83928  
 TI Atmospheric plasma deposition of hydrophobic/oil-repellent coatings with improved durability on glass/ceramic windows  
 IN Durandeau, Anne; Montigaud, Herve; Abbott, Fabrice; Huignard, Arnaud  
 PA Saint-Gobain Glass France, Fr.  
 SO Fr. Demande, 28pp.

CODEN: FRXXBL

DT Patent

LA French

FAN.CNT 1

	PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
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PI	FR 2902422	A1	20071221	FR 2006-52159	20060616
	WO 2007144536	A1	20071221	WO 2007-FR51421	20070612
	W: AE, AG, AL, AM, AT, AU, AZ, BA, BB, BG, BH, BR, BW, BY, BZ, CA, CH, CN, CO, CR, CU, CZ, DE, DK, DM, DO, DZ, EC, EE, EG, ES, FI, GB, GD, GE, GH, GM, GT, HN, HR, HU, ID, IL, IN, IS, JP, KE, KG, KM, KN, KP, KR, KZ, LA, LC, LK, LR, LS, LT, LU, LY, MA, MD, ME, MG, MK, MN, MW, MX, MY, MZ, NA, NG, NI, NO, NZ, OM, PG, PH, PL, PT, RO, RS, RU, SC, SD, SE, SG, SK, SL, SM, SV, SY, TJ, TM, TN, TR, TT, TZ, UA, UG, US, UZ, VC, VN, ZA, ZM, ZW				
	RW: AT, BE, BG, CH, CY, CZ, DE, DK, EE, ES, FI, FR, GB, GR, HU, IE, IS, IT, LT, LU, LV, MC, MT, NL, PL, PT, RO, SE, SI, SK, TR, BF, BJ, CF, CG, CI, CM, GA, GN, GQ, GW, ML, MR, NE, SN, TD, TG, BW, GH, GM, KE, LS, MW, MZ, NA, SD, SL, SZ, TZ, UG, ZM, ZW, AM, AZ, BY, KG, KZ, MD, RU, TJ, TM				

PRAI FR 2006-52159 A 20060616

RE.CNT 3 THERE ARE 3 CITED REFERENCES AVAILABLE FOR THIS RECORD  
ALL CITATIONS AVAILABLE IN THE RE FORMAT

L10 ANSWER 6 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN

AN 2007:980718 CAPLUS

DN 147:376451

TI Method for constructing surface enhanced substrate with metal ordered structure

IN Lu, Nan; Yang, Bingjie; Huang, Chunyu; Chi, Lifeng

PA Jilin University, Peop. Rep. China

SO Faming Zhuanli Shenqing Gongkai Shuomingshu, 30pp.

CODEN: CNXXEV

DT Patent

LA Chinese

FAN.CNT 1

	PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
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PI	CN 101024483	A	20070829	CN 2007-10055453	20070327
PRAI	CN 2007-10055453		20070327		

L10 ANSWER 7 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN

AN 2007:1362199 CAPLUS

DN 148:336717

TI Reproducible microfabrication method for a metal oxide film on a chemical template of self-assembled monolayer

AU Shirahata, Naoto; Sakka, Yoshio; Hozumi, Atsushi

CS National Institute for Materials Science (NIMS), Japan

SO Transactions of the Materials Research Society of Japan (2007), 32(3), 755-758

CODEN: TMRJE3; ISSN: 1382-3469

PB Materials Research Society of Japan

DT Journal

LA English

RE.CNT 18 THERE ARE 18 CITED REFERENCES AVAILABLE FOR THIS RECORD  
ALL CITATIONS AVAILABLE IN THE RE FORMAT

L10 ANSWER 8 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN

AN 2006:1124679 CAPLUS

DN 145:463186

TI Method of forming self-organizing monomolecular film and utilization of the same

IN Saito, Nagahiro; Ishizaki, Takahiro; Takai, Osamu  
 PA National University Corporation Nagoya University, Japan  
 SO PCT Int. Appl., 53pp.  
 CODEN: PIXXD2  
 DT Patent  
 LA Japanese  
 FAN.CNT 1

	PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
PI	WO 2006112408	A1	20061026	WO 2006-JP307962	20060414
	W: AE, AG, AL, AM, AT, AU, AZ, BA, BB, BG, BR, BW, BY, BZ, CA, CH, CN, CO, CR, CU, CZ, DE, DK, DM, DZ, EC, EE, EG, ES, FI, GB, GD, GE, GH, GM, HR, HU, ID, IL, IN, IS, JP, KE, KG, KM, KN, KP, KR, KZ, LC, LK, LR, LS, LT, LU, LV, LY, MA, MD, MG, MK, MN, MW, MX, MZ, NA, NG, NI, NO, NZ, OM, PG, PH, PL, PT, RO, RU, SC, SD, SE, SG, SK, SL, SM, SY, TJ, TM, TN, TR, TT, TZ, UA, UG, US, UZ, VC, VN, YU, ZA, ZM, ZW				
	RW: AT, BE, BG, CH, CY, CZ, DE, DK, EE, ES, FI, FR, GB, GR, HU, IE, IS, IT, LT, LU, LV, MC, NL, PL, PT, RO, SE, SI, SK, TR, BF, BJ, CF, CG, CI, CM, GA, GN, GQ, GW, ML, MR, NE, SN, TD, TG, BW, GH, GM, KE, LS, MW, MZ, NA, SD, SL, SZ, TZ, UG, ZM, ZW, AM, AZ, BY, KG, KZ, MD, RU, TJ, TM				
	JP 4065962	B2	20080326	JP 2007-528126	20060414
PRAI	JP 2005-118932	A	20050415		
	WO 2006-JP307962	W	20060414		

RE.CNT 7 THERE ARE 7 CITED REFERENCES AVAILABLE FOR THIS RECORD  
 ALL CITATIONS AVAILABLE IN THE RE FORMAT

L10 ANSWER 9 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
 AN 2006:1009344 CAPLUS  
 DN 145:378870  
 TI Falling acceleration of droplets on the water-repellent solid surface and control methods therefor and structures having controlled water-repellent solid surfaces  
 IN Suzuki, Shunsuke; Nakajima, Akira; Sakai, Munetoshi  
 PA Kanagawa Academy of Science and Technology, Japan; Tokyo Institute of Technology  
 SO Jpn. Kokai Tokkyo Koho, 8pp.  
 CODEN: JKXXAF  
 DT Patent  
 LA Japanese  
 FAN.CNT 1

	PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
PI	JP 2006257337	A	20060928	JP 2005-79144	20050318
PRAI	JP 2005-79144		20050318		

L10 ANSWER 10 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
 AN 2006:1085199 CAPLUS  
 DN 146:35674  
 TI Method for identical dye molecule emitting different color fluorescent light by substrate induction  
 IN Lu, Nan; Hu, Wei; Hao, Juanyuan; Chi, Lifeng  
 PA Jilin University, Peop. Rep. China  
 SO Faming Zhuanli Shenqing Gongkai Shuomingshu, 24pp.  
 CODEN: CNXXEV  
 DT Patent  
 LA Chinese  
 FAN.CNT 1

	PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
PI	CN 1844300	A	20061011	CN 2006-10016744	20060404

L10 ANSWER 11 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
AN 2006:641508 CAPLUS  
DN 145:183229  
TI Surface modification of silicon and polydimethylsiloxane  
surfaces with vapor-phase-deposited ultrathin fluorosilane films for  
biomedical nanodevices  
AU Bhushan, Bharat; Hansford, Derek; Lee, Kang Kug  
CS Nanotribology Laboratory for Information Storage and MEMS/NEMS, The Ohio  
State University, Columbus, OH, 43202, USA  
SO Journal of Vacuum Science & Technology, A: Vacuum, Surfaces, and Films  
(2006), 24(4), 1197-1202  
CODEN: JVTAD6; ISSN: 0734-2101  
PB American Institute of Physics  
DT Journal  
LA English  
RE.CNT 10 THERE ARE 10 CITED REFERENCES AVAILABLE FOR THIS RECORD  
ALL CITATIONS AVAILABLE IN THE RE FORMAT

L10 ANSWER 12 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
AN 2005:902015 CAPLUS  
DN 143:233933  
TI Rain-proof glass windows with a silicon-containing hydrophobic  
surface of improved durability  
IN Duran, Maxime; Huignard, Arnaud  
PA Saint-Gobain Glass France, Fr.  
SO Fr. Demande, 32 pp.  
CODEN: FRXXBL  
DT Patent  
LA French  
FAN.CNT 1

PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
PI FR 2866643	A1	20050826	FR 2004-50343	20040224
FR 2866643	B1	20060526		
WO 2005084943	A2	20050915	WO 2005-FR50119	20050223
WO 2005084943	A3	20051103		
W:	AE, AG, AL, AM, AT, AU, AZ, BA, BB, BG, BR, BW, BY, BZ, CA, CH, CN, CO, CR, CU, CZ, DE, DK, DM, DZ, EC, EE, EG, ES, FI, GB, GD, GE, GH, GM, HR, HU, ID, IL, IN, IS, JP, KE, KG, KP, KR, KZ, LC, LK, LR, LS, LT, LU, LV, MA, MD, MG, MK, MN, MW, MX, MZ, NA, NI, NO, NZ, OM, PG, PH, PL, PT, RO, RU, SC, SD, SE, SG, SK, SL, SM, SY, TJ, TM, TN, TR, TT, TZ, UA, UG, US, UZ, VC, VN, YU, ZA, ZM, ZW			
RW:	BW, GH, GM, KE, LS, MW, MZ, NA, SD, SL, SZ, TZ, UG, ZM, ZW, AM, AZ, BY, KG, KZ, MD, RU, TJ, TM, AT, BE, BG, CH, CY, CZ, DE, DK, EE, ES, FI, FR, GB, GR, HU, IE, IS, IT, LT, LU, MC, NL, PL, PT, RO, SE, SI, SK, TR, BF, BJ, CF, CG, CI, CM, GA, GN, GQ, GW, ML, MR, NE, SN, TD, TG			
EP 1720808	A2	20061115	EP 2005-728106	20050223
R:	AT, BE, BG, CH, CY, CZ, DE, DK, EE, ES, FI, FR, GB, GR, HU, IE, IS, IT, LI, LT, LU, MC, NL, PL, PT, RO, SE, SI, SK, TR			
CN 1946646	A	20070411	CN 2005-80012900	20050223
BR 2005007935	A	20070717	BR 2005-7935	20050223
JP 2007523776	T	20070823	JP 2007-500274	20050223
IN 2006KN02325	A	20070525	IN 2006-KN2325	20060817
MX 2006PA09574	A	20061107	MX 2006-PA9574	20060823
PRAI FR 2004-50343	A	20040224		
WO 2005-FR50119	W	20050223		

RE.CNT 2 THERE ARE 2 CITED REFERENCES AVAILABLE FOR THIS RECORD  
ALL CITATIONS AVAILABLE IN THE RE FORMAT

L10 ANSWER 13 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
AN 2005:106536 CAPLUS  
DN 142:361489  
TI Fabrication of Superhydrophobic Surfaces by Self-Assembly and Their  
Water-Adhesion Properties  
AU Song, Xiaoyan; Zhai, Jin; Wang, Yilin; Jiang, Lei  
CS Center for Molecular Sciences, Institute of Chemistry, Chinese Academy of  
Sciences, Beijing, 100080, Peop. Rep. China  
SO Journal of Physical Chemistry B (2005), 109(9), 4048-4052  
CODEN: JPCBFK; ISSN: 1520-6106  
PB American Chemical Society  
DT Journal  
LA English  
RE.CNT 31 THERE ARE 31 CITED REFERENCES AVAILABLE FOR THIS RECORD  
ALL CITATIONS AVAILABLE IN THE RE FORMAT

L10 ANSWER 14 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
AN 2005:410625 CAPLUS  
DN 143:88377  
TI Micropatterning of SrBi<sub>2</sub>Ta<sub>2</sub>O<sub>9</sub> ferroelectric thin films using a selective  
deposition technique combined with patterned self-assembled monolayers and  
liquid-source misted chemical deposition  
AU Takakuwa, Atsushi; Ishida, Masaya; Shimoda, Tatsuya  
CS Technology Platform Research Center, SEIKO EPSON Corporation, Nagano,  
399-0293, Japan  
SO Japanese Journal of Applied Physics, Part 1: Regular Papers, Short Notes &  
Review Papers (2005), 44(4A), 1897-1900  
CODEN: JAPNDE  
PB Japan Society of Applied Physics  
DT Journal  
LA English  
RE.CNT 8 THERE ARE 8 CITED REFERENCES AVAILABLE FOR THIS RECORD  
ALL CITATIONS AVAILABLE IN THE RE FORMAT

L10 ANSWER 15 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
AN 2005:702603 CAPLUS  
DN 144:208350  
TI Nanoscale patterning of protein using electron beam lithography of  
organosilane self-assembled monolayers  
AU Zhang, Guo-Jun; Tanii, Takashi; Zako, Tamotsu; Hosaka, Takumi; Miyake,  
Takeo; Kanari, Yuzo; Funatsu, Takashi; Ohdomari, Iwao  
CS Nanotechnology Research Center and Institute of Biomedical Engineering,  
Waseda University, Tokyo, 162-0041, Japan  
SO Small (2005), 1(8-9), 833-837  
CODEN: SMALBC; ISSN: 1613-6810  
PB Wiley-VCH Verlag GmbH & Co. KGaA  
DT Journal  
LA English  
RE.CNT 22 THERE ARE 22 CITED REFERENCES AVAILABLE FOR THIS RECORD  
ALL CITATIONS AVAILABLE IN THE RE FORMAT

L10 ANSWER 16 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
AN 2005:422268 CAPLUS  
DN 144:281105  
TI Macro- and nanotribological properties of organosilane monolayers prepared  
by a chemical vapor adsorption method on silicon substrates  
AU Ishida, H.; Koga, T.; Morita, M.; Otsuka, H.; Takahara, A.  
CS Graduate School of Engineering, Kyushu University, Fukuoka, 812-8581,  
Japan  
SO Tribology Letters (2005), 19(1), 3-8  
CODEN: TRLEFS; ISSN: 1023-8883  
PB Springer

DT Journal  
 LA English  
 RE.CNT 21 THERE ARE 21 CITED REFERENCES AVAILABLE FOR THIS RECORD  
 ALL CITATIONS AVAILABLE IN THE RE FORMAT

L10 ANSWER 17 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
 AN 2004:1060574 CAPLUS  
 DN 142:40141  
 TI Thin film forming method and thin film forming substance  
 IN Kudo, Ichiro; Saito, Atsushi; Arita, Hiroaki  
 PA Konica Minolta Holdings, Inc., Japan  
 SO U.S. Pat. Appl. Publ., 32 pp.  
 CODEN: USXXCO

DT Patent  
 LA English

FAN.CNT 1

	PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
PI	US 20040247886	A1	20041209	US 2004-858704	20040601
	JP 2004360039	A	20041224	JP 2003-162032	20030606
	JP 2005023381	A	20050127	JP 2003-191025	20030703
	WO 2004108984	A1	20041216	WO 2004-JP7860	20040531
	W: AE, AG, AL, AM, AT, AU, AZ, BA, BB, BG, BR, BW, BY, BZ, CA, CH, CN, CO, CR, CU, CZ, DE, DK, DM, DZ, EC, EE, EG, ES, FI, GB, GD, GE, GH, GM, HR, HU, ID, IL, IN, IS, KE, KG, KP, KR, KZ, LC, LK, LR, LS, LT, LU, LV, MA, MD, MG, MK, MN, MW, MX, MZ, NA, NI, NO, NZ, OM, PG, PH, PL, PT, RO, RU, SC, SD, SE, SG, SK, SL, SY, TJ, TM, TN, TR, TT, TZ, UA, UG, US, UZ, VC, VN, YU, ZA, ZM, ZW				
	RW: BW, GH, GM, KE, LS, MW, MZ, NA, SD, SL, SZ, TZ, UG, ZM, ZW, AM, AZ, BY, KG, KZ, MD, RU, TJ, TM, AT, BE, BG, CH, CY, CZ, DE, DK, EE, ES, FI, FR, GB, GR, HU, IE, IT, LU, MC, NL, PL, PT, RO, SE, SI, SK, TR, BF, BJ, CF, CG, CI, CM, GA, GN, GQ, GW, ML, MR, NE, SN, TD, TG				
	EP 1643002	A1	20060405	EP 2004-735520	20040531
	R: AT, BE, CH, DE, DK, ES, FR, GB, GR, IT, LI, LU, NL, SE, MC, PT, IE, SI, LT, LV, FI, RO, MK, CY, AL, TR, BG, CZ, EE, HU, PL, SK, HR				
	CN 1798865	A	20060705	CN 2004-80015446	20040531
PRAI	JP 2003-162032	A	20030606		
	JP 2003-191025	A	20030703		
	WO 2004-JP7860	W	20040531		

L10 ANSWER 18 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
 AN 2004:162231 CAPLUS  
 DN 140:227524  
 TI Method of coating microelectromechanical devices  
 IN Yang, Zhihao  
 PA Eastman Kodak Company, USA  
 SO U.S. Pat. Appl. Publ., 7 pp.  
 CODEN: USXXCO

DT Patent  
 LA English

FAN.CNT 1

	PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
PI	US 20040037956	A1	20040226	US 2002-225846	20020822
	US 6808745	B2	20041026		
	EP 1416064	A2	20040506	EP 2003-77499	20030811
	EP 1416064	A3	20050615		
	EP 1416064	B1	20080507		
	R: AT, BE, CH, DE, DK, ES, FR, GB, GR, IT, LI, LU, NL, SE, MC, PT, IE, SI, LT, LV, FI, RO, MK, CY, AL, TR, BG, CZ, EE, HU, SK				
	JP 2004084073	A	20040318	JP 2003-298568	20030822

PRAI US 2002-225846 A 20020822  
RE.CNT 7 THERE ARE 7 CITED REFERENCES AVAILABLE FOR THIS RECORD  
ALL CITATIONS AVAILABLE IN THE RE FORMAT

L10 ANSWER 19 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
AN 2004:759183 CAPLUS  
DN 141:268689  
TI Antisoiling optical films with good oil repellency and displays equipped therewith  
IN Oka, Shigeki; Ikeda, Toshiyuki  
PA Konica Minolta Holdings, Inc., Japan  
SO Jpn. Kokai Tokkyo Koho, 55 pp.  
CODEN: JKXXAF  
DT Patent  
LA Japanese  
FAN.CNT 1

	PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
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PI	JP 2004258348	A	20040916	JP 2003-49281	20030226
PRAI	JP 2003-49281		20030226		
OS	MARPAT 141:268689				

L10 ANSWER 20 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
AN 2004:674693 CAPLUS  
DN 141:168967  
TI Development of substrate surface modification methods for biochemical immobilization in biochips  
IN Kim, Hun-Ki; Lee, Jung-Suk; Lim, Geun-Bae; Lee, Young-Sun  
PA Samsung Electronics Co., Ltd., S. Korea  
SO Jpn. Kokai Tokkyo Koho, 11 pp.  
CODEN: JKXXAF  
DT Patent  
LA Japanese  
FAN.CNT 1

	PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
	-----	---	-----	-----	-----
PI	JP 2004229663	A	20040819	JP 2004-18353	20040127
	KR 2004069063	A	20040804	KR 2003-5486	20030128
	EP 1452232	A2	20040901	EP 2004-1606	20040126
	EP 1452232	A3	20050720		
	R: AT, BE, CH, DE, DK, ES, FR, GB, GR, IT, LI, LU, NL, SE, MC, PT, IE, SI, LT, LV, FI, RO, MK, CY, AL, TR, BG, CZ, EE, HU, SK				
	US 20040185480	A1	20040923	US 2004-765366	20040127
	CN 1519562	A	20040811	CN 2004-10005810	20040128
PRAI	KR 2003-5486	A	20030128		

L10 ANSWER 21 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
AN 2004:198553 CAPLUS  
DN 140:236678  
TI Method and apparatus for manufacturing anti-reflective films  
IN Tanaka, Takeshi  
PA Konica Minolta Holdings Inc., Japan  
SO Jpn. Kokai Tokkyo Koho, 40 pp.  
CODEN: JKXXAF  
DT Patent  
LA Japanese  
FAN.CNT 1

	PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
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PI	JP 2004075738	A	20040311	JP 2002-234607	20020812
PRAI	JP 2002-234607		20020812		



L10 ANSWER 22 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
AN 2004:121659 CAPLUS  
DN 140:231666  
TI Formation of molecular templates for fabricating on-chip biosensing devices  
AU Niwa, Daisuke; Yamada, Yukiko; Homma, Takayuki; Osaka, Tetsuya  
CS Department of Applied Chemistry, School of Science and Engineering, Waseda University, Shinjuku, Tokyo, 169-8555, Japan  
SO Journal of Physical Chemistry B (2004), 108(10), 3240-3245  
CODEN: JPCBFK; ISSN: 1520-6106  
PB American Chemical Society  
DT Journal  
LA English  
RE.CNT 26 THERE ARE 26 CITED REFERENCES AVAILABLE FOR THIS RECORD  
ALL CITATIONS AVAILABLE IN THE RE FORMAT

L10 ANSWER 23 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
AN 2004:157226 CAPLUS  
DN 140:383314  
TI Vapor pressures of precursors for the CVD of silicon-based films  
AU Alcott, Gregory R.; van de Sanden, Richard M. C. M.; Kondic, Sascha; Linden, Joannes L.  
CS Department of Applied Physics, Eindhoven University of Technology, Eindhoven, 5600 MB, Neth.  
SO Chemical Vapor Deposition (2004), 10(1), 20-22  
CODEN: CVDEFX; ISSN: 0948-1907  
PB Wiley-VCH Verlag GmbH & Co. KGaA  
DT Journal  
LA English  
RE.CNT 6 THERE ARE 6 CITED REFERENCES AVAILABLE FOR THIS RECORD  
ALL CITATIONS AVAILABLE IN THE RE FORMAT

L10 ANSWER 24 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
AN 2003:256239 CAPLUS  
DN 139:37976  
TI Self-assembled monolayer coatings on nanostencils for the reduction of materials adhesion  
AU Kolbel, Marius; Tjerkstra, R. Willem; Kim, Gyuman; Brugger, Jurgen; van Rijn, Cees J. M.; Nijdam, Wietze; Huskens, Jurriaan; Reinhoudt, David N.  
CS Laboratory of Supramolecular Chemistry and Technology MESA+ Research Institute, University of Twente, Enschede, NL-7500 AE, Neth.  
SO Advanced Functional Materials (2003), 13(3), 219-224  
CODEN: AFMDC6; ISSN: 1616-301X  
PB Wiley-VCH Verlag GmbH & Co. KGaA  
DT Journal  
LA English  
RE.CNT 17 THERE ARE 17 CITED REFERENCES AVAILABLE FOR THIS RECORD  
ALL CITATIONS AVAILABLE IN THE RE FORMAT

L10 ANSWER 25 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
AN 2003:466411 CAPLUS  
DN 139:217781  
TI Preparation of hard and ultra water-repellent silicon oxide films by microwave plasma-enhanced CVD at low substrate temperatures  
AU Wu, Yunying; Sugimura, Hiroyuki; Inoue, Yasushi; Takai, Osamu  
CS Center for Integrated Research in Science and Engineering, Nagoya University, Nagoya, 464-8603, Japan  
SO Thin Solid Films (2003), 435(1-2), 161-164  
CODEN: THSFAP; ISSN: 0040-6090  
PB Elsevier Science B.V.

DT Journal  
LA English  
RE.CNT 7 THERE ARE 7 CITED REFERENCES AVAILABLE FOR THIS RECORD  
ALL CITATIONS AVAILABLE IN THE RE FORMAT

L10 ANSWER 26 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
AN 2003:101697 CAPLUS  
DN 138:344356  
TI Imaging micropatterned organosilane self-assembled monolayers on  
silicon by means of scanning electron microscopy and Kelvin probe  
force microscopy  
AU Wu, Yunying; Hayashi, Kazuyuki; Saito, Nagahiro; Sugimura, Hiroyuki;  
Takai, Osamu  
CS Department of Materials Processing Engineering, Graduate School of  
Engineering, Nagoya University, Nagoya, 464-8603, Japan  
SO Surface and Interface Analysis (2003), 35(1), 94-98  
CODEN: SIANDQ; ISSN: 0142-2421  
PB John Wiley & Sons Ltd.  
DT Journal  
LA English  
RE.CNT 26 THERE ARE 26 CITED REFERENCES AVAILABLE FOR THIS RECORD  
ALL CITATIONS AVAILABLE IN THE RE FORMAT

L10 ANSWER 27 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
AN 2002:638152 CAPLUS  
DN 137:177507  
TI Method for making thin film and electronic apparatus  
IN Furusawa, Masahiro; Shimoda, Tatsuya  
PA Seiko Epson Corporation, Japan  
SO U.S. Pat. Appl. Publ., 13 pp.  
CODEN: USXXCO

DT Patent  
LA English

FAN.CNT 1

	PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
PI	US 20020114887	A1	20020822	US 2001-26635	20011227
	US 6780465	B2	20040824		
	JP 2002275629	A	20020925	JP 2001-398535	20011227
PRAI	JP 2000-403229	A	20001228		

RE.CNT 5 THERE ARE 5 CITED REFERENCES AVAILABLE FOR THIS RECORD  
ALL CITATIONS AVAILABLE IN THE RE FORMAT

L10 ANSWER 28 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
AN 2002:539411 CAPLUS  
DN 137:101690  
TI Formation method of silicon thin film  
IN Furusawa, Masahiro; Miyashita, Satoru; Yudasaka, Kazuo; Shimoda, Tatsuya;  
Yokoyama, Yasuaki; Matsuki, Yasuo; Takeuchi, Yasumasa  
PA Seiko Epson Corp., Japan; JSR Ltd.  
SO Jpn. Kokai Tokkyo Koho, 7 pp.  
CODEN: JKXXAF

DT Patent

LA Japanese

FAN.CNT 1

	PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
PI	JP 2002203794	A	20020719	JP 2000-402809	20001228
	JP 3745959	B2	20060215		
	US 20030087110	A1	20030508	US 2001-28712	20011228
	US 6846513	B2	20050125		
PRAI	JP 2000-402809	A	20001228		

OS MARPAT 137:101690

L10 ANSWER 29 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN

AN 2002:675485 CAPLUS

DN 137:193392

TI Regulation of the surface potential of silicon substrates in micrometer scale with organosilane self-assembled monolayers

AU Hayashi, Kazuyuki; Saito, Nagahiro; Sugimura, Hiroyuki; Takai, Osamu; Nakagiri, Nobuyuki

CS Department of Materials Processing Engineering Graduate School of Engineering, Nagoya University, Nagoya, 464-8603, Japan

SO Langmuir (2002), 18(20), 7469-7472

CODEN: LANGD5; ISSN: 0743-7463

PB American Chemical Society

DT Journal

LA English

RE.CNT 23 THERE ARE 23 CITED REFERENCES AVAILABLE FOR THIS RECORD  
ALL CITATIONS AVAILABLE IN THE RE FORMAT

L10 ANSWER 30 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN

AN 2002:697175 CAPLUS

DN 137:300353

TI Surface potential images of self-assembled monolayers patterned by organosilanes. Ab initio molecular orbital calculations

AU Saito, N.; Hayashi, K.; Sugimura, H.; Takai, O.; Nakagiri, N.

CS Department of Materials Engineering, Graduate School of Engineering, Nagoya University, Nagoya, 464-8603, Japan

SO Surface and Interface Analysis (2002), 34(1), 601-605

CODEN: SIANDQ; ISSN: 0142-2421

PB John Wiley & Sons Ltd.

DT Journal

LA English

RE.CNT 21 THERE ARE 21 CITED REFERENCES AVAILABLE FOR THIS RECORD  
ALL CITATIONS AVAILABLE IN THE RE FORMAT

L10 ANSWER 31 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN

AN 2002:110853 CAPLUS

DN 136:407289

TI Lateral force on fluoroalkylsilane self-assembled monolayers dependent on molecular ordering

AU Sugimura, Hiroyuki; Ushiyama, Kazuya; Hozumi, Atsushi; Takai, Osamu

CS Department of Materials Processing Engineering, Graduate School of Engineering, Nagoya University, Furo-cho, Chikusa, Nagoya, 464-8603, Japan

SO Journal of Vacuum Science & Technology, B: Microelectronics and Nanometer Structures (2002), 20(1), 393-395

CODEN: JVTBD9; ISSN: 0734-211X

PB American Institute of Physics

DT Journal

LA English

RE.CNT 22 THERE ARE 22 CITED REFERENCES AVAILABLE FOR THIS RECORD  
ALL CITATIONS AVAILABLE IN THE RE FORMAT

L10 ANSWER 32 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN

AN 2002:570922 CAPLUS

DN 137:175370

TI Surface potential contrasts between silicon surfaces covered and uncovered with an organosilane self-assembled monolayer

AU Hayashi, Kazuyuki; Saito, Nagahiro; Sugimura, Hiroyuki; Takai, Osamu; Nakagiri, Nobuyuki

CS Graduate School of Engineering, Department of Materials Processing Engineering, Nagoya University, Chikusa, Nagoya, 464-8603, Japan

SO Ultramicroscopy (2002), 91(1-4), 151-156

CODEN: ULTRD6; ISSN: 0304-3991

PB Elsevier Science B.V.

DT Journal

LA English

RE.CNT 26 THERE ARE 26 CITED REFERENCES AVAILABLE FOR THIS RECORD  
ALL CITATIONS AVAILABLE IN THE RE FORMAT

L10 ANSWER 33 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN

AN 2001:380495 CAPLUS

DN 134:368295

TI Preparation of water-repellent hard surface

IN Nakajima, Akira; Watanabe, Toshiya; Hashimoto, Kazuhito; Fujishima, Akira

PA Center for Advanced Science and Technology Incubation, Ltd., Japan

SO PCT Int. Appl., 31 pp.

CODEN: PIXXD2

DT Patent

LA Japanese

FAN.CNT 1

	PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
	-----	----	-----	-----	-----
PI	WO 2001036190	A1	20010525	WO 2000-JP7841	20001108
	W: CA, CN, KR, US				
	RW: AT, BE, CH, CY, DE, DK, ES, FI, FR, GB, GR, IE, IT, LU, MC, NL, PT, SE, TR				
	JP 2001207123	A	20010731	JP 2000-268026	20000905
PRAI	JP 1999-326093	A	19991116		
	JP 2000-268026	A	20000905		

RE.CNT 17 THERE ARE 17 CITED REFERENCES AVAILABLE FOR THIS RECORD  
ALL CITATIONS AVAILABLE IN THE RE FORMAT

L10 ANSWER 34 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN

AN 2001:345268 CAPLUS

DN 134:356571

TI Formation of surface expansion pattern and substrate having the pattern

IN Minami, Tsutomu; Tatsumisago, Masahiro; Tadanaga, Kiyoharu; Matsuda, Atsunori

PA Japan

SO Jpn. Kokai Tokkyo Koho, 10 pp.

CODEN: JKXXAF

DT Patent

LA Japanese

FAN.CNT 1

	PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
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PI	JP 2001129474	A	20010515	JP 1999-312088	19991102
PRAI	JP 1999-312088		19991102		

L10 ANSWER 35 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN

AN 2001:219584 CAPLUS

DN 135:37563

TI  $\zeta$ -Potentials of planar silicon plates covered with alkyl- and fluoroalkylsilane self-assembled monolayers

AU Hozumi, A.; Sugimura, H.; Yokogawa, Y.; Kameyama, T.; Takai, O.

CS Agency of Industrial Science and Technology, National Industrial Research Institute of Nagoya, Hirate-cho, Kita-ku, Nagoya, 462-8510, Japan

SO Colloids and Surfaces, A: Physicochemical and Engineering Aspects (2001), 182(1-3), 257-261

CODEN: CPEAEH; ISSN: 0927-7757

PB Elsevier Science B.V.

DT Journal

LA English

RE.CNT 22 THERE ARE 22 CITED REFERENCES AVAILABLE FOR THIS RECORD

## ALL CITATIONS AVAILABLE IN THE RE FORMAT

L10 ANSWER 36 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
AN 2000:179936 CAPLUS  
DN 132:215825  
TI Vapor deposition targets for antistaining or  
water-repellent coatings and antireflective materials having the coatings  
IN Tomikawa, Tsunetoshi; Watanabe, Hiroki; Ohata, Koichi; Takeda, Akira  
PA Toppan Printing Co., Ltd., Japan  
SO Jpn. Kokai Tokkyo Koho, 4 pp.  
CODEN: JKXXAF  
DT Patent  
LA Japanese  
FAN.CNT 1

	PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
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PI	JP 2000080465	A	20000321	JP 1998-249538	19980903
PRAI	JP 1998-249538		19980903		
OS	MARPAT 132:215825				

L10 ANSWER 37 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
AN 2000:13129 CAPLUS  
DN 132:187551  
TI Micropatterning of Alkyl- and Fluoroalkylsilane Self-Assembled Monolayers  
Using Vacuum Ultraviolet Light  
AU Sugimura, Hiroyuki; Ushiyama, Kazuya; Hozumi, Atsushi; Takai, Osamu  
CS Department of Materials Processing Engineering Graduate School of  
Engineering, Nagoya University, Chikusa Nagoya, 464-8603, Japan  
SO Langmuir (2000), 16(3), 885-888  
CODEN: LANGD5; ISSN: 0743-7463  
PB American Chemical Society  
DT Journal  
LA English  
RE.CNT 46 THERE ARE 46 CITED REFERENCES AVAILABLE FOR THIS RECORD  
ALL CITATIONS AVAILABLE IN THE RE FORMAT

L10 ANSWER 38 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
AN 2000:609376 CAPLUS  
DN 133:285182  
TI Morphology of mesoporous silica grown on organic surfaces: effects of  
surface functional groups and microstructures  
AU Hozumi, Atsushi; Yokogawa, Yoshiyuki; Kameyama, Tetsuya; Hiraku,  
Katsumasa; Sugimura, Hiroyuki; Takai, Osamu; Okido, Masazumi  
CS Bioceramics Laboratory, Ceramics Technology Department, National  
Industrial Research Institute of Nagoya, Nagoya, 462-8510, Japan  
SO Materials Research Society Symposium Proceedings (2000),  
599(Mineralization in Natural and Synthetic Biomaterials), 255-259  
CODEN: MRSPDH; ISSN: 0272-9172  
PB Materials Research Society  
DT Journal  
LA English  
RE.CNT 21 THERE ARE 21 CITED REFERENCES AVAILABLE FOR THIS RECORD  
ALL CITATIONS AVAILABLE IN THE RE FORMAT

L10 ANSWER 39 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
AN 1999:783781 CAPLUS  
DN 132:37023  
TI Method for providing water-repellent coatings on optical substrates  
IN Anthes, Uwe; Dombrowski, Reiner  
PA Merck Patent G.m.b.H., Germany  
SO Eur. Pat. Appl., 8 pp.  
CODEN: EPXXDW

DT Patent  
LA German

FAN.CNT 1

	PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
PI	EP 962511	A1	19991208	EP 1999-110077	19990522
	EP 962511	B1	20051116		
	R: AT, BE, CH, DE, DK, ES, FR, GB, GR, IT, LI, LU, NL, SE, MC, PT, IE, SI, LT, LV, FI, RO				
	DE 19825100	A1	19991216	DE 1998-19825100	19980605
	ES 2252887	T3	20060516	ES 1999-110077	19990522
	JP 2000080331	A	20000321	JP 1999-153778	19990601
	JP 3549440	B2	20040804		
	KR 2000005904	A	20000125	KR 1999-20580	19990604
	US 6296793	B1	20011002	US 1999-325796	19990604
	US 20010033893	A1	20011025	US 2001-892712	20010628
PRAI	DE 1998-19825100	A	19980605		
	US 1999-325796	A3	19990604		

OS MARPAT 132:37023

RE.CNT 6 THERE ARE 6 CITED REFERENCES AVAILABLE FOR THIS RECORD  
ALL CITATIONS AVAILABLE IN THE RE FORMAT

L10 ANSWER 40 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN

AN 1998:314379 CAPLUS

DN 128:315457

TI Water-repellent silicon oxide film, its manufacture, and hard  
water-repellent silicon oxide film

IN Takai, Osamu; Hozumi, Atsushi

PA Takai, Osamu, Japan

SO Jpn. Kokai Tokkyo Koho, 17 pp.

CODEN: JKXXAF

DT Patent

LA Japanese

FAN.CNT 1

	PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
PI	JP 10130844	A	19980519	JP 1997-68766	19970321
	JP 3945664	B2	20070718		
PRAI	JP 1996-237017	A	19960906		

L10 ANSWER 41 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN

AN 1998:315071 CAPLUS

DN 129:84819

TI Preparation of functionally graded films by microwave plasma-enhanced  
chemical vapor deposition. Silicon oxide  
films having water-repellent surfaces

AU Hozumi, Atsushi; Kajita, Iwao; Takai, Osamu

CS Grad. Sch., Nagoya Univ., Nagoya, 464-8603, Japan

SO Hyomen Gijutsu (1998), 49(5), 489-495

CODEN: HYGIEX; ISSN: 0915-1869

PB Hyomen Gijutsu Kyokai

DT Journal

LA Japanese

L10 ANSWER 42 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN

AN 1998:739058 CAPLUS

DN 130:171637

TI Preparation of silicon oxide films having a water-repellent  
layer by multiple-step microwave plasma-enhanced chemical vapor  
deposition

AU Hozumi, Atsushi; Takai, Osamu

CS Dep. Mater. Processing Eng., Grad. Sch. of Eng., Nagoya Univ., Furo-cho,

Chikusa-ku, Nagoya, 464-8603, Japan  
SO Thin Solid Films (1998), 334(1,2), 54-59  
CODEN: THSFAP; ISSN: 0040-6090  
PB Elsevier Science S.A.  
DT Journal  
LA English

RE.CNT 10 THERE ARE 10 CITED REFERENCES AVAILABLE FOR THIS RECORD  
ALL CITATIONS AVAILABLE IN THE RE FORMAT

L10 ANSWER 43 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
AN 1997:545693 CAPLUS  
DN 127:212640  
OREF 127:41217a,41220a  
TI Effects of methyl and perfluoro-alkyl groups on water repellency of  
silicon oxide films prepared by microwave plasma-enhanced chemical  
vapor deposition  
AU Hozumi, Atsushi; Kondo, Takahiro; Kajita, Iwao; Sekoguchi, Hiroki;  
Sugimoto, Nobuhisa; Takai, Osamu  
CS Department of Materials Processing Engineering, Nagoya University, Nagoya,  
464-01, Japan  
SO Japanese Journal of Applied Physics, Part 1: Regular Papers, Short Notes &  
Review Papers (1997), 36(7B), 4959-4963  
CODEN: JAPNDE; ISSN: 0021-4922  
PB Japanese Journal of Applied Physics  
DT Journal  
LA English  
RE.CNT 16 THERE ARE 16 CITED REFERENCES AVAILABLE FOR THIS RECORD  
ALL CITATIONS AVAILABLE IN THE RE FORMAT

L10 ANSWER 44 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
AN 1997:622716 CAPLUS  
DN 127:310357  
OREF 127:60645a,60648a  
TI Coating of transparent water-repellent thin films by plasma-enhanced  
CVD  
AU Takai, Osamu; Hozumi, Atsushi; Sugimoto, Nobuhisa  
CS Department of Materials Processing Engineering, Nagoya University,  
Chikusa-ku, Nagoya, 464-01, Japan  
SO Journal of Non-Crystalline Solids (1997), 218, 280-285  
CODEN: JNCSBJ; ISSN: 0022-3093  
PB Elsevier  
DT Journal  
LA English  
RE.CNT 12 THERE ARE 12 CITED REFERENCES AVAILABLE FOR THIS RECORD  
ALL CITATIONS AVAILABLE IN THE RE FORMAT

L10 ANSWER 45 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
AN 1996:652522 CAPLUS  
DN 125:278702  
OREF 125:52095a,52098a  
TI Manufacture of water-repellent coatings by high-frequency plasma chemical  
vapor deposition  
IN Hozumi, Atsushi; Kato, Yoshifumi; Takai, Osamu; Kakigi, Shinsuke  
PA Toyota Automatic Loom Works, Ltd., Japan; Toyota Jido Shotsuki Seisakusho  
KK  
SO Jpn. Kokai Tokkyo Koho, 5 pp.  
CODEN: JKXXAF  
DT Patent  
LA Japanese  
FAN.CNT 1

PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
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PI JP 08217898 A 19960827 JP 1995-49148 19950213  
JP 3482724 B2 20040106  
PRAI JP 1995-49148 19950213

L10 ANSWER 46 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
AN 1996:286422 CAPLUS  
DN 124:345256  
OREF 124:64123a,64126a  
TI Fluorine-contained films with high water-repellency and transparency  
prepared by RF plasma-enhanced CVD  
AU Hozumi, A.; Kakinoki, N.; Asai, Y.; Takai, O.  
CS Sch. Eng., Nagoya Univ., Nagoya, 464-01, Japan  
SO Journal of Materials Science Letters (1996), 15(8), 675-677  
CODEN: JMSLD5; ISSN: 0261-8028  
PB Chapman & Hall  
DT Journal  
LA English

L10 ANSWER 47 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
AN 1997:659403 CAPLUS  
DN 127:310439  
OREF 127:60657a,60660a  
TI Effects of substrate temperature on properties of fluorine contained  
silicon oxide films prepared by microwave plasma-enhanced  
CVD  
AU Sugimoto, Nobuhisa; Hozumi, Atsushi; Takai, Osamu  
CS Dep. Mater. Processing Eng., Nagoya Univ., Nagoya, 464-01, Japan  
SO Han'guk Pyomyon Konghak Hoechi (1996), 29(5), 577-584  
CODEN: HPKHEL; ISSN: 1225-8024  
PB Korean Institute of Surface Engineering  
DT Journal  
LA English

RE.CNT 13 THERE ARE 13 CITED REFERENCES AVAILABLE FOR THIS RECORD  
ALL CITATIONS AVAILABLE IN THE RE FORMAT

L10 ANSWER 48 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
AN 1995:330786 CAPLUS  
DN 122:108850  
OREF 122:20441a,20444a  
TI Water-repellent fluorine-containing silicon oxide coatings  
IN Sumi, Toshio; Matsuda, Atsunori; Ogino, Etsuo; Soejima, Ayako  
PA Nippon Sheet Glass Co Ltd, Japan  
SO Jpn. Kokai Tokkyo Koho, 7 pp.  
CODEN: JKXXAF  
DT Patent  
LA Japanese

FAN.CNT 1

	PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
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PI	JP 06228755	A	19940816	JP 1993-16332	19930203
PRAI	JP 1993-16332		19930203		

L10 ANSWER 49 OF 49 CAPLUS COPYRIGHT 2008 ACS on STN  
AN 1994:109608 CAPLUS  
DN 120:109608  
OREF 120:19339a,19342a  
TI Heat- and chemical-resistant organic thin films and their manufacture  
IN Morikawa, Juko; Kasanuki, Juji; Yanagisawa, Yoshihiro; Matsuda, Hiroshi  
PA Canon Kk, Japan  
SO Jpn. Kokai Tokkyo Koho, 8 pp.  
CODEN: JKXXAF  
DT Patent



LA Japanese

FAN.CNT 1

	PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
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PI	JP 05220887	A	19930831	JP 1992-28417	19920214
	JP 3025091	B2	20000327		
PRAI	JP 1992-28417		19920214		

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ALL L# QUERIES AND ANSWER SETS ARE DELETED AT LOGOFF

LOGOFF? (Y)/N/HOLD:y

COST IN U.S. DOLLARS

SINCE FILE

TOTAL

ENTRY

SESSION

FULL ESTIMATED COST

88.49

445.42

STN INTERNATIONAL LOGOFF AT 16:06:20 ON 11 JUN 2008